

Form PTO 1449
(Modified)U.S. DEPARTMENT OF COMMERCE
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249687US2SERIAL NO.
10/790,828

LIST OF REFERENCES CITED BY APPLICANT

APPLICANT
Masakiyo MATSUMURA, et al.FILING DATE
March 3, 2004

GROUP

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA					
	AB					
	AC					
	AD					
	AE					
	AF					
	AG					
	AH					
	AI					
	AJ					
	AK					
	AL					

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
MS	AM	2000-306859	11/02/2000	JAPAN (with corr. EP 1 047 119)		X
MS	AN	1 047 119	10/25/2000	EUROPE		
	AO					
	AP					

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)			
MS	AQ	C-H. OH, et al., Japanese Journal of Applied Physics, vol. 37, part 2, no. 5A, pages L492 - L495, "A NOVEL PHASE-MODULATED EXCIMER-LASER CRYSTALLIZATION METHOD OF SILICON THIN FILMS", May 1, 1998	
MS	AR	M. NAKATA, et al., Japanese Journal of Applied Physics, vol. 40, part 1, no. 5A, pages 3049-3054, "A NEW NUCLEATION-SITE-CONTROL EXCIMER-LASER-CRYSTALLIZATION METHOD", May 2001	
MS	AS	M. MATSUMURA, IDW '02 AMD5-1, pages 263-266, "ADVANCED LASER-CRYSTALLIZATION TECHNOLOGIES OF SI FOR HIGH-PERFORMANCE TFTs", 2001	
MS	AT	International Display Workshops, pages 1-6, "ADVANCED LASER-CRYSTALLIZATION TECHNOLOGIES OF SI FOR HIGH-PERFORMANCE TFTs", 2002	
MS	AU	M. MATSUMURA, Journal of The Surface Science Society of Japan, vol. 21, no. 5, pages 278-287, "PREPARATION OF ULTRA-LARGE GRAIN SILICON THIN-FILMS BY EXCIMER-LASER", May 2000	
MS	AV	K. INOUE, et al., The Institute of Electronics, Information and Communication Engineers Transactions, vol. J85-C, no. 8, pages 624-629, "AMPLITUDE AND PHASE MODULATED EXCIMER-LASER MELT-REGROWTH METHOD OF SILICON THIN-FILMS - A NEW GROWTH METHOD OF 2-D POSITION-CONTROLLED LARGE - GRAINS", August 2002	<input type="checkbox"/> Additional References sheet(s) attached
			Date Considered 10/02/2006

Examiner

/Matthew Song/

*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.